

Evactron[®] 25



Evactron[®] 25 De-Contaminator

XEI SCIENTIFIC introduces our exciting new Evactron[®]25 De-Contaminator (D-C) for cleaning scanning electron microscopes.

We're pushing the frontiers electron microscope cleaning technology to improve resolution and imaging time for 21st century needs.

Evactron[®]D-C cleaning uses a unique, cutting edge process for remote plasma production of oxygen radicals that flow downstream through your system, removing hydrocarbons.

These new user friendly Evactron[®]D-C models optimize remote plasma cleaning perfectly to the needs of the user.

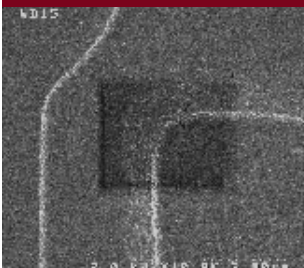
*Gentle. Fast.
Convenient and
Effective Cleaning*

*Convenient **Tabletop Model** for removal of atmospheric molecular contamination, oils and hydrocarbons*

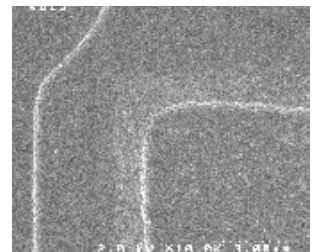
IN SEMS AND FIBS

- **Easy to operate and setup**
- **Start cleaning by using vent and evacuation controls for chamber**
- **Preset pressure, power, and time settings from front panel or computer interface**
- **Uses air, no special gases needed**
- **Plasma and nitrogen purge cleaning can be combined in cycles for maximum cleaning efficiency**
- **Advanced plasma detection logic**
- **Cleaning and error logs record cleaning history and aids trouble shooting**
- **Electronic Chassis: H, W, D: 5.5" x 9" x 7"**
- **RF Power: 5 - 20 Watts at 13.56 MHz**
- **KF 40 vacuum mounting flange**
- **100-240 VAC 50/60 Hz input**
- **Shipping-22 lb. (10 kgms)**

Try the Evactron[®] Process in your lab, free, [shipping charges apply] for 30 days by placing an evaluation PO by January 15, 2008



Unwanted Artifact



After Evactron[®] Cleaning

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